ABSTRACT OF THE DISCLOSURE

In one embodiment, a wafer-handling robot in a wafer processing system is automatically calibrated by determining an orientation of the robot relative to a chassis of the wafer processing system, determining hand-off coordinates of a load port in the

5   wafer processing system, and determining hand-off coordinates of a load lock in the wafer processing system. Also disclosed is a calibration fixture for automatically calibrating the wafer-handling robot to the load port.